Form PTO 1449	U.S. DEPARTMENT OF COMMERCE			ATTY DOCKET NO.		SERIAL NO.		
(Modified)		PATENT AND TRAI	DEMARK OFFICE	240438US2		New Application		
				APPLICANT				
LIST OF REFERENCES CITED BY APPLICANT			Hirokazu SAYAMA, et al.					
				FILING DATE		GROUP		
				Herewith				
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB FILING DATE CLASS IF APPROPRIATE		
	AA							
	AB							
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			FC	REIGN PATENT DOCUMENTS				
		DOCUMENT	DATE	COUNTRY	TRANSLATION			
		NUMBER	DAIL			YES		NO
	AO	2002-93921	03/29/02	Japan (with English extract)				×
	AP	2001-284558	10/12/01	Japan (with English extract)		<u> </u>		X
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	AR							
	AS							
	AT							
	AU							
	AV	L		<u> </u>		l		
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)								
	J. WELSER, et al., "NMOS AND PMOS TRANSISTORS FABRICATED IN STRAINED SILICON/RELAXED SILICON-GERMANIUM STRUCTURES", Proc. of International Electron Device Meeting 1992, IEDM 92, pgs. 1000 - 1002.							
	AX	T. MIZUNO, et al., "HIGH PERFORMANCE STRAINED-Si p-MOSFETs ON SiGe-ON-INSULATOR SUBSTRATES FABRICATED BY SIMOX TECHNOLOGY", Proc. of International Electron Device Meeting 1999, IEEE, pgs. 934 - 936.						
	AY							
	AZ				Additional References sheet(s) attached			
Examiner					Date Considered			
				ot citation is in conformance with MPEP 60 m with next communication to applicant.	09; Draw li	ne through	citation	if not in

Docket No.

240438US2

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Hirokazu SAYAMA, et al.

SERIAL NO: New Application

GAU:

FILED:

Herewith

EXAMINER:

FOR:

SEMICONDUCTOR DEVICE INCLUDING GATE ELECTRODE FOR APPLYING TENSILE STRESS TO

SILICON SUBSTRATE, AND METHOD OF MANUFACTURING THE SAME

# INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

Applicant(s) wish to disclose the following information.

#### REFERENCES

- The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

### **RELATED CASES**

- ☐ Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

## **CERTIFICATION**

- ☐ Each item of information contained in this information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

## **DEPOSIT ACCOUNT**

Please charge any additional fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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